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PATENT

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

**In re Application of:**

Pan et al.

**Serial No.:** 09/614,113

**Filed:** July 12, 2000

**For:** TECHNIQUE FOR ELIMINATION  
OF PITTING ON SILICON SUBSTRATE  
DURING GATE STACK ETCH

**Confirmation No.:** 1710

**Examiner:** D. Deo

**Group Art Unit:** 1765

**Attorney Docket No.:** 2269-2915.3US  
(96-0149.02/US)

CERTIFICATE OF MAILING

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6/4/2003

Date

*Rachael M. Harris*  
Signature

Rachael M. Harris  
Name (Type/Print)

**AMENDMENT UNDER 37 C.F.R. §1.116**

Mail Stop AF  
Commissioner for Patents  
PO Box 1450  
Alexandria, VA 22313-1450

Sir:

The following amendments and remarks are filed in response to the Examiner's remarks in the Final Office Action mailed April 8, 2003, the three-month shortened statutory period for response to which expires on July 8, 2003. This response is submitted on or before two months from the mailing date of the Final Office Action.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 6 of this paper.